



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#9/Amend A
Q Free
11/12/02

In re Application of)

Group Art Unit: 2825

Maximilian A. Biberger)

Examiner: Caridad Everhart

5 Serial No. 09/841,800)

Filed: April 24, 2001)

**AMENDMENT AND RESPONSE TO
OFFICE ACTION MAILED ON
JULY 29, 2002**

For: **METHOD FOR DEPOSITING**)

10 **METAL FILM AND METAL**)

DEPOSITION CLUSTER TOOL)

INCLUDING SUPERCRITICAL)

DRYING/CLEANING MODULE)

162 North Wolfe Road
Sunnyvale, CA 94086
(408) 530-9700

15 Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

20 **AMENDMENTS**

Please amend the Application as follows:

In the Claims:

25 Please amend the claims as follows (clean version of amended claims):

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1 19. (Amended) A method of depositing a film on a substrate comprising the steps of:
2 maintaining supercritical carbon dioxide from a first module in contact with the
3 substrate to remove a sorbate selected from the group consisting of an absorbate
4 and an adsorbate from the substrate, thereby forming a desorbed substrate; and

11/05/2002 DTESSEM1 00000082 09841800